

Customer No. 22,852  
Attorney Docket No. 04208.0245

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
PCT/JP2005/06840 )  
 )  
 )  
Akira UMEDA )  
 )  
Application No.: 10/594,317 )  
 )  
 )  
Filed: August 17, 2007 )  
 )  
For: METHOD OF MEASURING  
TRANSVERSE SENSITIVITY  
OF SENSOR FOR  
DETECTING ACCELERATION  
AND ACCELERATION  
MEASURING METHOD

**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§1.56 and 1.97(b), applicant brings to the Examiner's attention the documents listed on the attached Form PTO/SB/08. Copies of the listed foreign patent documents are attached. Applicant respectfully requests that the Examiner consider the documents listed on attached Form PTO/SB/08 and indicate that they were considered by making an appropriate notation on this form.

This Information Disclosure Statement is being filed with the above-referenced application.

The following are listed on the accompanying PTO/SB/08 and are in a non-English language:

1. Japanese Patent Application Publication No 2000-338128.
2. Akira UMEDA *et al.*, "Revisit the Calibration of Inertia Sensors", The Transactions E of the Institute of Electrical Engineers of Japan, vol. 125, pp. 108-117, (2005).
3. Akira UMEDA *et al.*, " Calibration of three-axis accelerometers using a three-dimensional vibration generator and three laser interferometers" SENSORS AND ACTUATORS A, pp. 93-101, (2004).
4. Akira UMEDA *et al.*, " Calibration of Three-axis Accelerometers as a Three-Dimensional Accelerometer Using a Three-Dimensional Vibration Generator and Laser Interferometers, Metrology Institute of Japan, National Institute of Advanced Industrial Science and Technology, pp. 38-45, (2004).

An English-language abstract of each document listed above is enclosed.

Also enclosed is an English-language international search report from the Japanese Patent Office in the PCT international application, from which this national phase U.S. application is derived, citing documents 1 and 2 above and setting forth the relevance thereof.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that the listed documents are material or constitute "prior art." If the Examiner applies the documents as prior art against any claim in the application and applicant determines that the cited documents do not constitutes "prior art" under United States law, applicant reserves the right to present to the Office the relevant facts and law regarding the appropriate status of such

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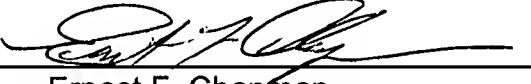
documents. Applicant further reserves the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should the document be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: August 17, 2007

By:   
Ernest F. Chapman  
Reg. No. 25,961

Enclosures  
DWH/FPD/sem

|  |   |    |   |                               |                    |
|--|---|----|---|-------------------------------|--------------------|
| IDS Form PTO/SB/08: Substitute for form 1449A/PTO  |   |    |   | <b>Complete if Known</b>      |                    |
| <b>INFORMATION DISCLOSURE<br/>STATEMENT BY APPLICANT</b><br><i>(Use as many sheets as necessary)</i> |   |    |   | <i>Application Number</i>     | 10/594,317         |
| Sheet  | 1 | of | 1 | <i>Filing Date</i>            | September 27, 2006 |
|  |   |    |   | <i>First Named Inventor</i>   | Akira UMEDA        |
|  |   |    |   | <i>Art Unit</i>               |                    |
|  |   |    |   | <i>Examiner Name</i>          |                    |
|  |   |    |   | <i>Attorney Docket Number</i> | 04208.0245         |

| <b>U.S. PATENTS AND PUBLISHED U.S. PATENT APPLICATIONS</b> |                       |  |   |   |   |
|--|-----------------------|--|---|---|---|
| Examiner Initials  | Cite No. <sup>1</sup> | Document Number                          | Issue or Publication Date<br>MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
|  |                       | Number-Kind Code <sup>2</sup> (if known) |   |   |   |
|  |                       |  |   |   |   |
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Note: Copies of the U.S. Patent Documents are not Required in IDS filed after October 21, 2004

| <b>FOREIGN PATENT DOCUMENTS</b> |                       |   |                                |   |   |
|---------------------------------|-----------------------|---|--------------------------------|---|---|
| Examiner Initials               | Cite No. <sup>1</sup> | Foreign Patent Document   | Publication Date<br>MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
|                                 |                       | Country Code <sup>3</sup> Number <sup>4</sup> Kind Code <sup>5</sup> (if known) |                                |   |   |
|                                 |                       | JP 2000-338128  | 12-08-2000                     | H. Takahashi et al.                             |   |
|                                 |                       |   |                                |   | Abstract  |
|                                 |                       |   |                                |   |   |
|                                 |                       |   |                                |   |   |

| <b>NON PATENT LITERATURE DOCUMENTS</b> |                       |  |  |  |                          |
|--|-----------------------|--|--|--|--------------------------|
| Examiner Initials                      | Cite No. <sup>1</sup> | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.                                |  |  | Translation <sup>6</sup> |
|  |                       | ISO5347-11:1993(E), "Methods for the calibration of vibration and shock pick-ups - Part 11: Testing of transverse vibration sensitivity", International Standard, pp. 296-297, (1993)  |  |  |                          |
|  |                       | ISO16063-11:1999(E), "Methods for the calibration of vibration and shock transducers - Part 11: Primary vibration calibration by laser interferometry", International Standard, pp. iii-iv and 1-27, (1999)  |  |  |                          |
|  |                       | ISO 5347-1:1993(E), "Methods for the calibration of vibration and shock pick-ups - Part 1: Primary vibration calibration by laser interferometry", International Standard, pp. 233-245, (1993)   |  |  |                          |
|  |                       | ISO 2041 : 1990 (E/F), "Vibration and Shock - Vocabulary", International Standard", pp. 47-105, (1990)   |  |  |                          |
|  |                       | Akira UMEDA et al., "Revisit the Calibration of Inertia Sensors", The Transactions E of the Institute of Electrical Engineers of Japan, vol. 125, pp. 108-117, (2005)  |  |  | Abstract                 |
|  |                       | Akira UMEDA et al., " Calibration of three-axis accelerometers using a three-dimensional vibration generator and three laser interferometers", SENSORS AND ACTUATORS A, pp.93-101, (2004)  |  |  | Abstract                 |
|  |                       | Akira UMEDA et al., " Calibration of Three-axis Accelerometers as a Three-Dimensional Accelerometer Using a Three-Dimensional Vibration Generator and Laser Interferometers, Metrology Institute of Japan, National Institute of Advanced Industrial Science and Technology, pp. 38-45, (2004) |  |  | Abstract                 |

|                    |                |                 |            |
|--------------------|----------------|-----------------|------------|
| Examiner Signature | /Robert Raevs/ | Date Considered | 10/08/2009 |
|--------------------|----------------|-----------------|------------|

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /R.R./